



PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 09/361,980
Filing Date: July 28, 1999
Applicant: Yasuaki Tsuzuki et al.
Group Art Unit: 1765
Examiner: L. Umez Eronini
Title: Method of Etching Metallic Thin Film on Thin Film Resistor
Attorney Docket: 4041J-000439

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Commissioner of Patents and Trademarks
Washington, D.C. 20231

AMENDMENT AND PETITION FOR EXTENSION OF TIME

Sir:

In response to the Office Action mailed December 19, 2001, Paper No. 12, please amend the application as follows and consider the remarks set forth below.

Applicant hereby petitions under the provisions of 37 C.F.R. § 1.136(a) for a one-month extension of time in which to respond to the outstanding Office Action. Applicant has included a Fee Transmittal with this response for such extension of time.

IN THE CLAIMS

Please cancel Claims 5, 6, 12-25 and 28-32; and amend Claims 7-11, 26 and 27. Applicant includes herewith an Attachment for Claim Amendments showing a